

# MAPS sensor for radiation imaging

*designed in 180 nm SOI CMOS technology*

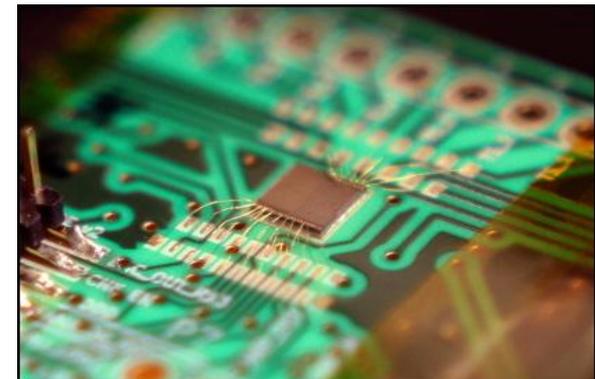
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3<sup>rd</sup> July 2017, iWoRiD 2017, Krakow, Poland



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# Outline

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- **Technology introduction**
- **Parameters of the chip**
- **SOI pixel**
- **Pixel design and simulations**
- **Measurement results**

**Poster 1:** **M. Kuklová**, *Radiation Imaging with a SOI-based Monolithic Pixel Chip*, poster session 05/07/2017, B21

**Poster 2:** **T. Benka**, *Characterization of pixel sensor designed in 180 nm SOI CMOS technology*, poster session 03/07/2017, B16

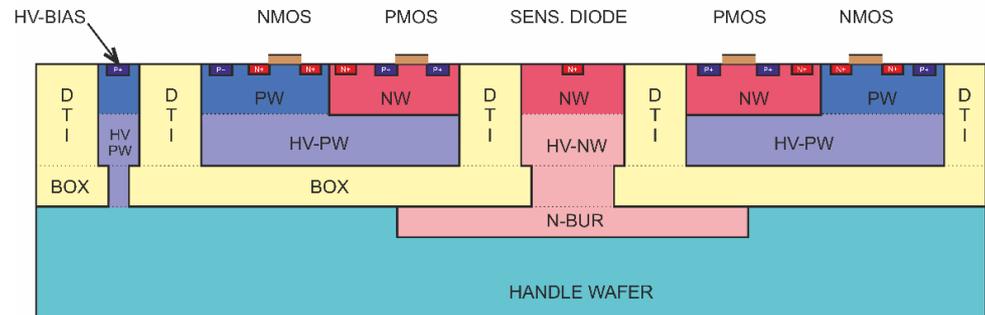
# Technology introduction

- SOI – Silicon on Insulation – “non-traditional”
- Non-depleted EPI-layer
- Medium resistivity handle wafer
- Deep submicron CMOS process
- High voltage compatible

Technology choice inspired by:

[1] T. Hemperik et al. A Monolithic active pixel sensor for ionizing radiation using a 180 nm HV/SOI process, arXiv:1412.3973

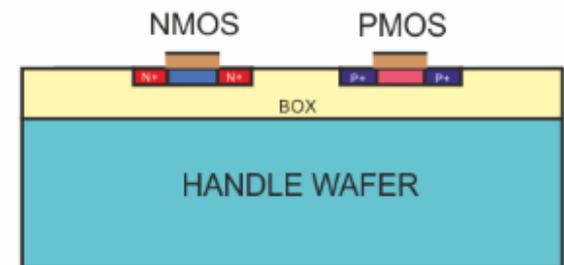
## non-depleted SOI CMOS process



- What does it mean for MAPS sensor:

- larger depleted zone (30  $\mu\text{m}$ ) @ 100 V  $\rightarrow$  larger signal
- sensing diode does not consume pixel area
- full CMOS FE in pixel
- substrate noise immunity
- SEU immunity

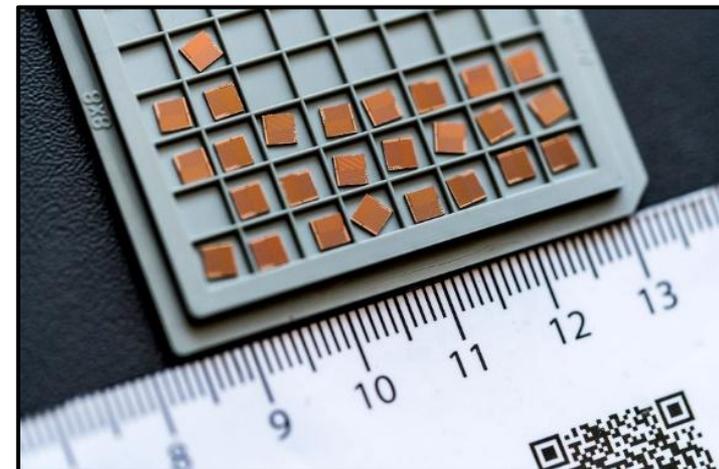
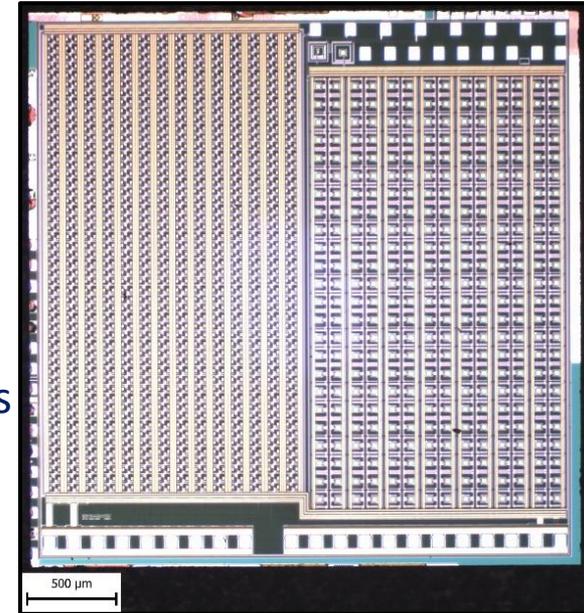
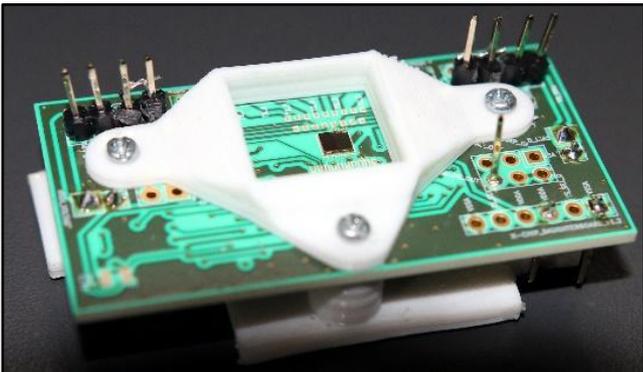
## FD SOI



# X-CHIP-02

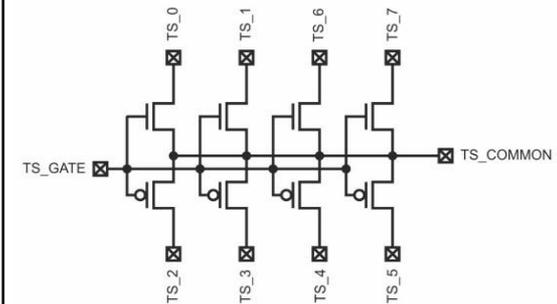
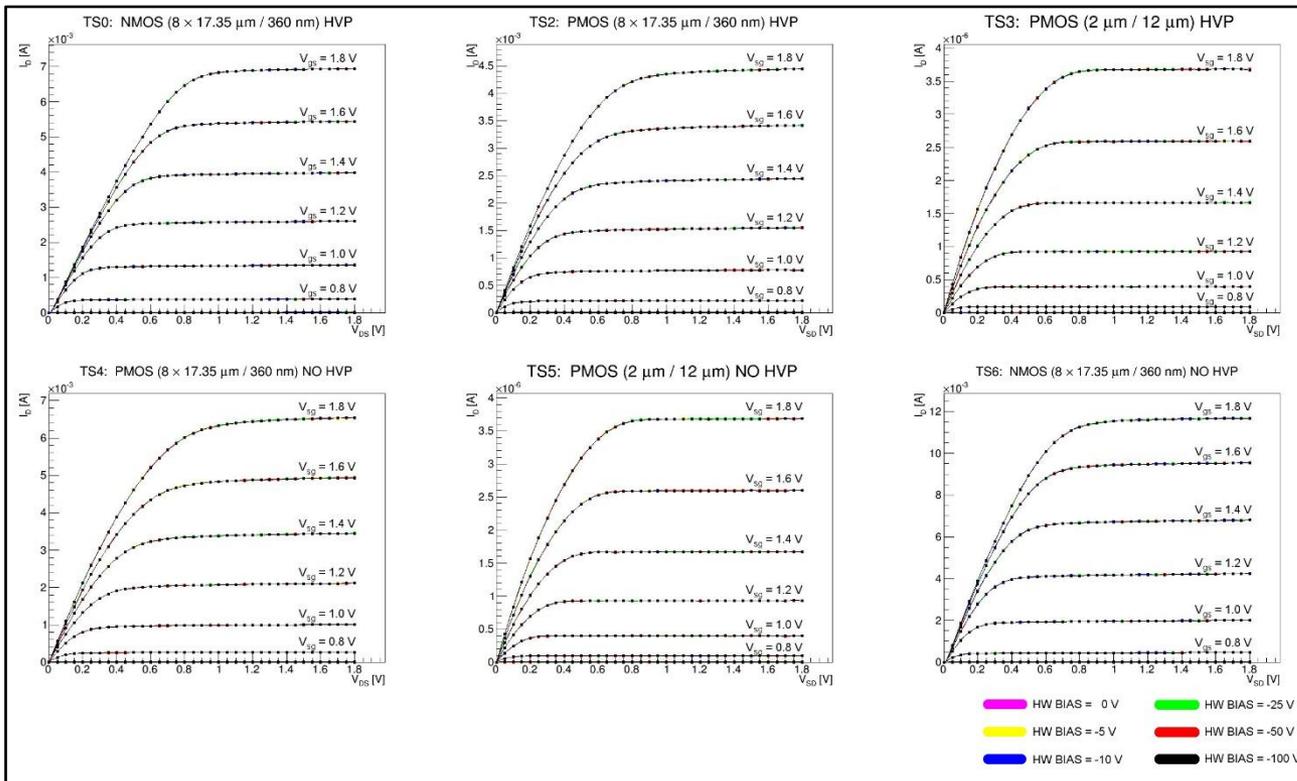
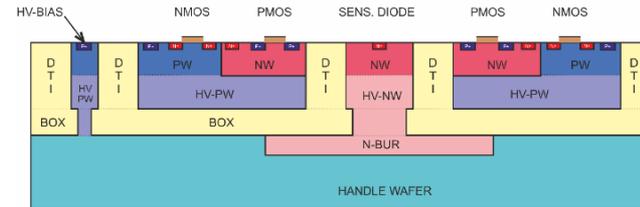
- **Two pixel matrices:** 50  $\mu\text{m}$  and 100  $\mu\text{m}$
- **Matrix dimensions:** 28 $\times$ 51 resp. 14 $\times$ 24 pixels
- **Sensitive area:** 1.4 $\times$ 2.55 resp. 1.4 $\times$ 2.8  $\text{mm}^2$
- **Chip thickness:** 300  $\mu\text{m}$  (partially depleted)
- **Process:** 6-metal 180 nm SOI-CMOS process
- **Core voltage:** 1.8 V
- **Sensor bias voltage:** -100 V
- **Design complexity:** 880 000 transistors

Test-pcb with X-CHIP-02



# Transistors (measurement)

- Non-depleted SOI does not suffer from back-gate effect
- Possibility to bias HW without influencing pixel electronics
- Radiation tolerance (?) → see poster of **T. Benka**

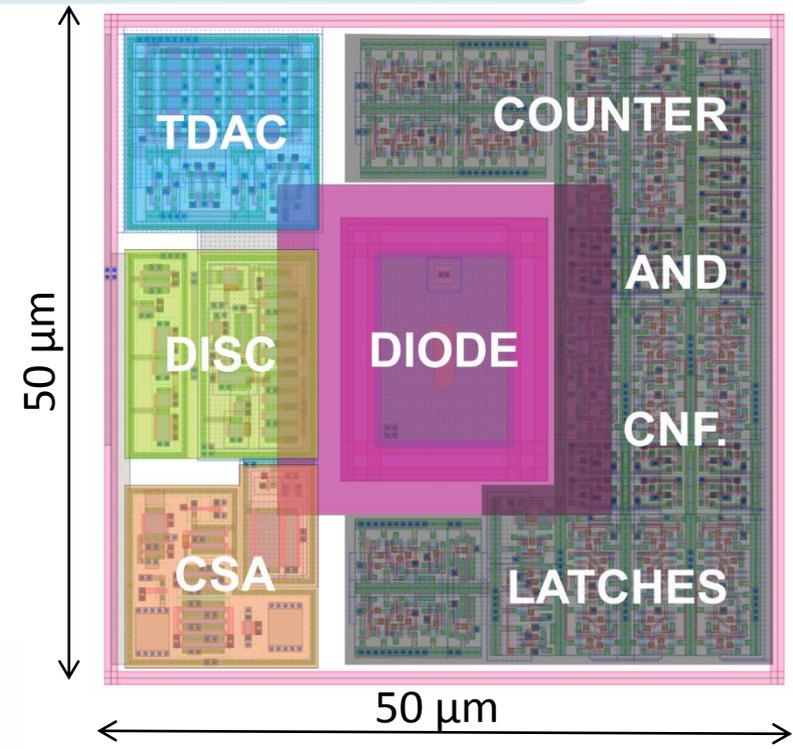


TS	Dimensions (W/L)	Type	HVP
0	17.35 μm × 8 / 360 nm	NMOS	YES
1	2 μm / 12 μm	NMOS	YES
2	17.35 μm × 8 / 360 nm	PMOS	YES
3	2 μm / 12 μm	PMOS	YES
4	17.35 μm × 8 / 360 nm	PMOS	NO
5	2 μm / 12 μm	PMOS	NO
6	17.35 μm × 8 / 360 nm	NMOS	NO
7	2 μm / 12 μm	NMOS	NO

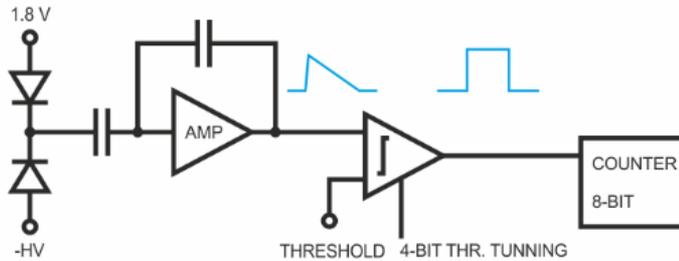
— broken gate (ESD)

# 50 $\mu\text{m}$ pixel design

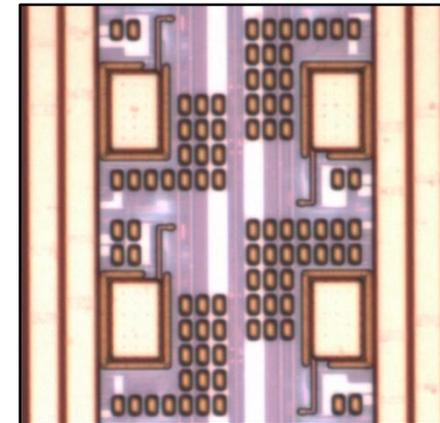
- MAPS with “*hybrid pixel like*” FE electronics
- 526 transistors per pixel
- Each pixel has “private” substrate
- Analog front-end + 8-bit hit-counter
  - power consumption: 5.2  $\mu\text{W}$



28x51  
pixels



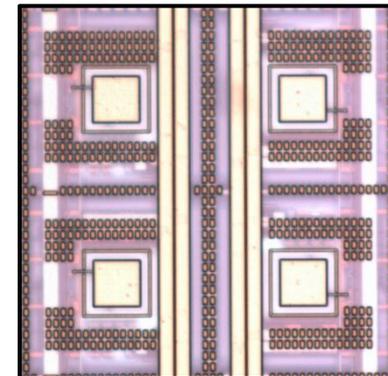
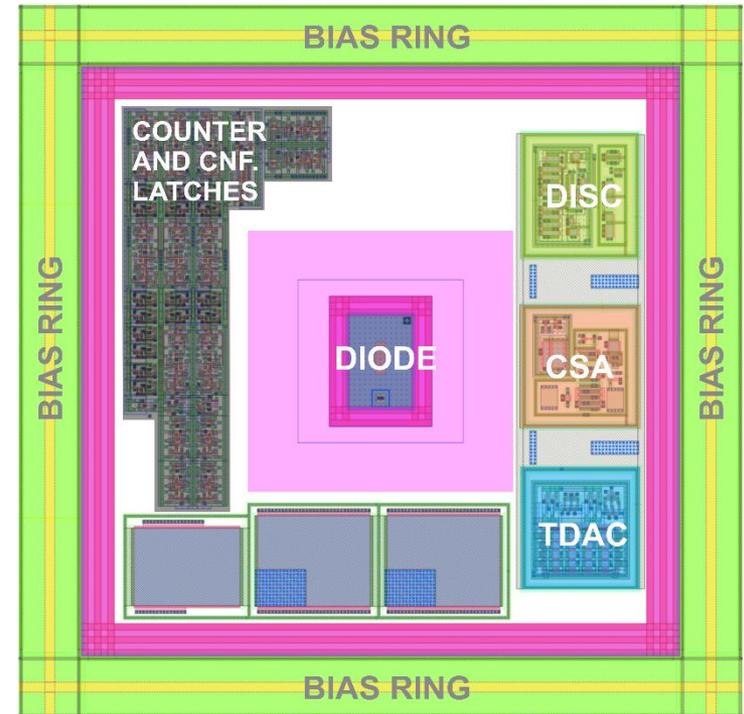
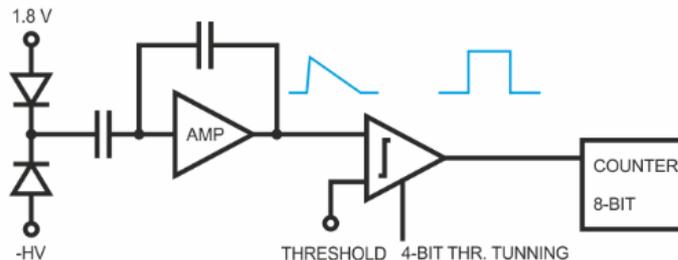
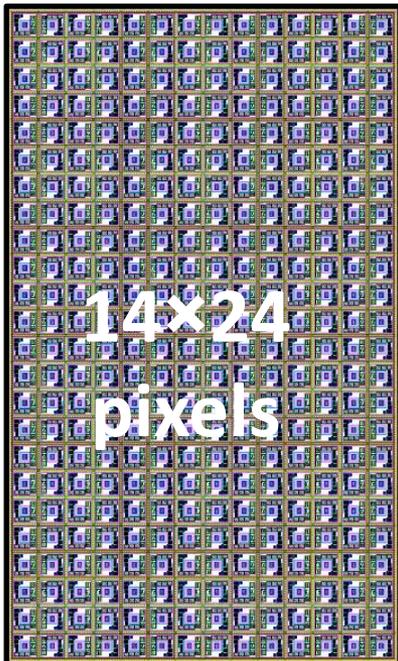
common bias ring of the handling wafer



micrograph of 2x2 pixels

# 100 $\mu\text{m}$ pixel design

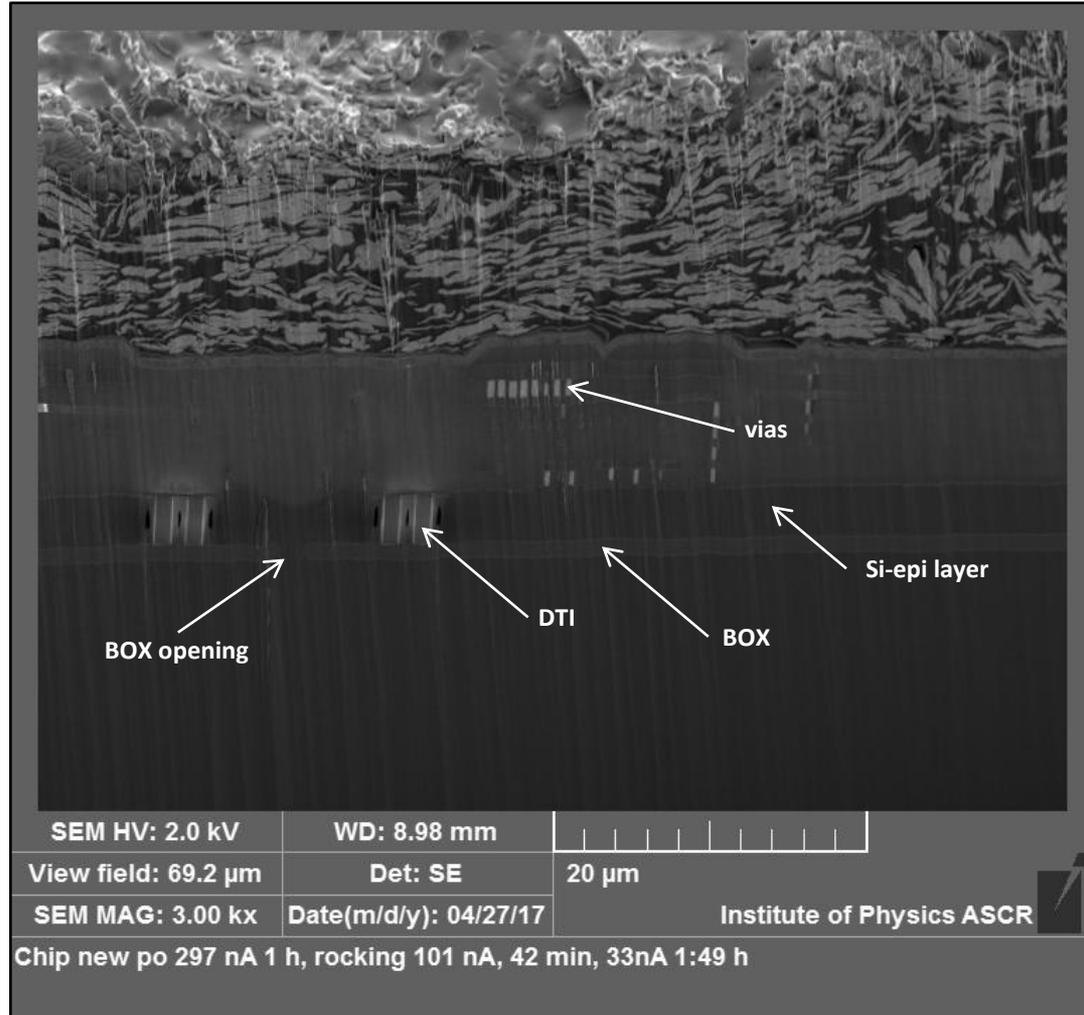
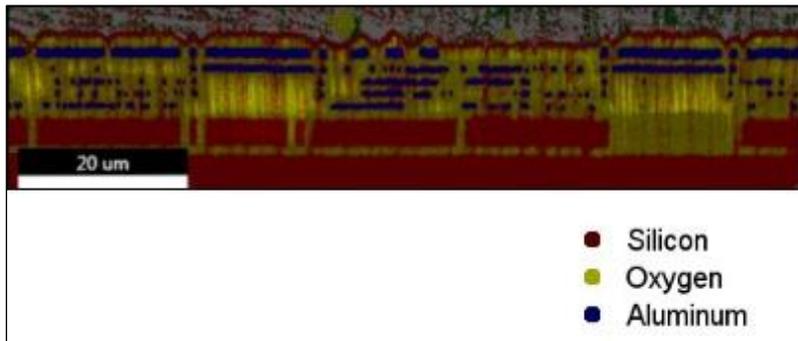
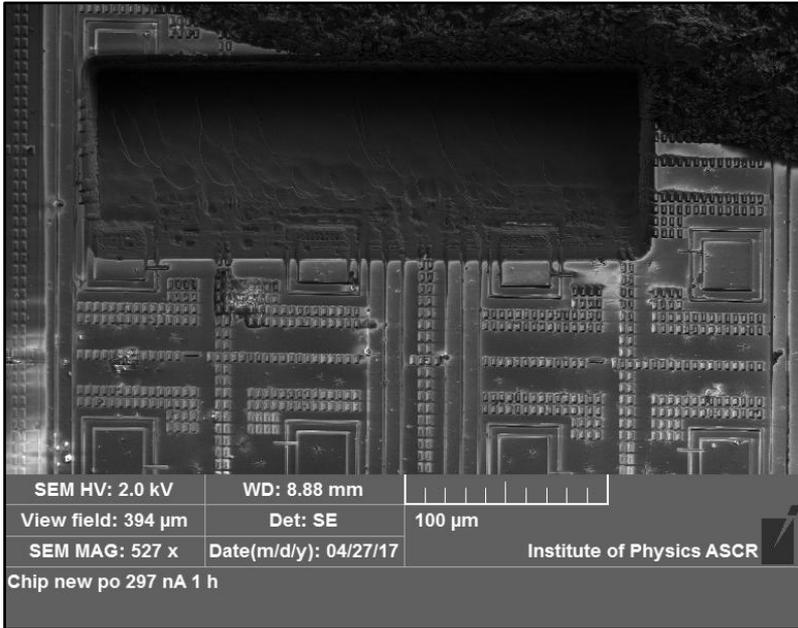
- Pixel electronics almost identical with 50  $\mu\text{m}$  pixels
- Local bias-ring
- Different coupling capacitor size:  
238 fF (50  $\mu\text{m}$  pixel) vs. 642 fF (100  $\mu\text{m}$  pixel)



micrograph of 2x2 pixels 7

# X-CHIP-02 disassembled

- Surface layers excavated by Focused Ion Beam (Xenon atoms)



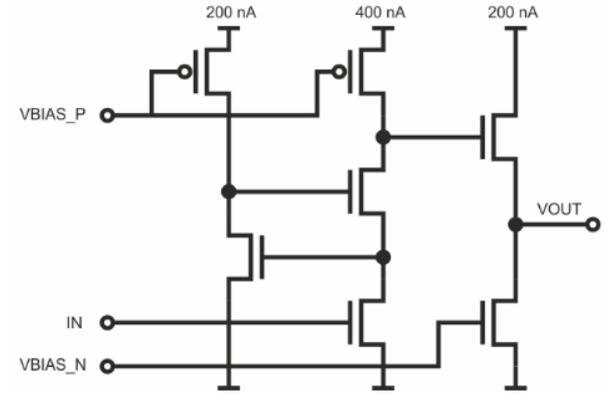
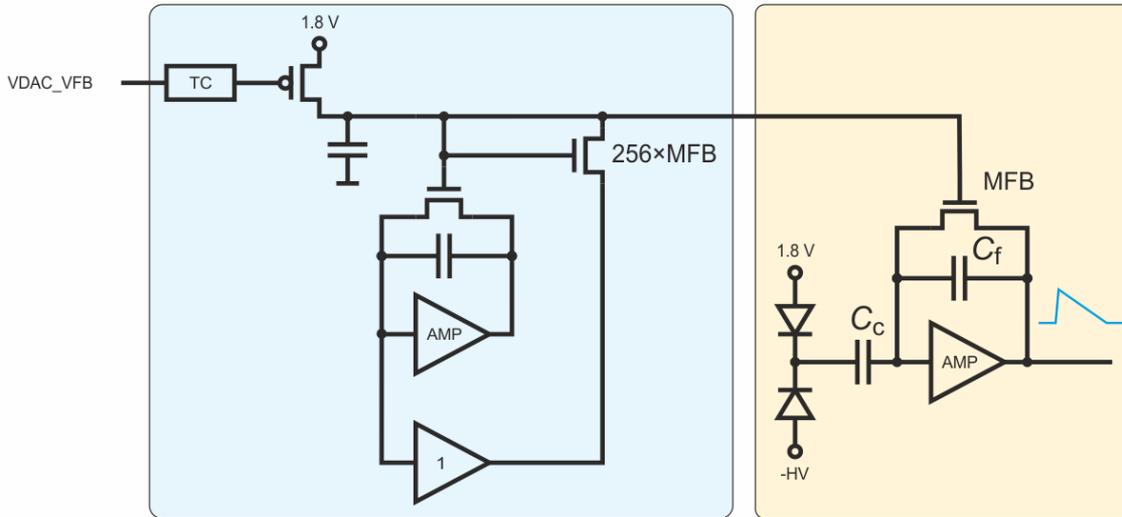
# Analog front-end – a closer look I.

- Charge Sensitive Amplifier (CSA):

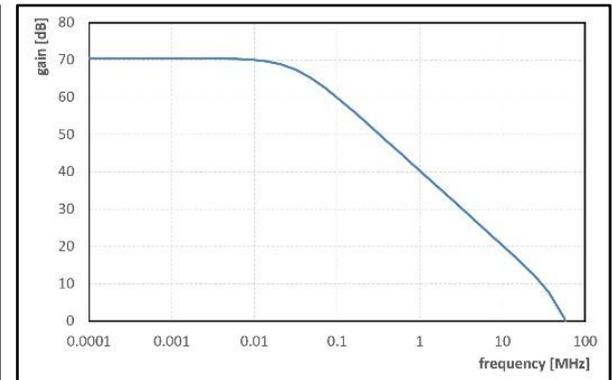
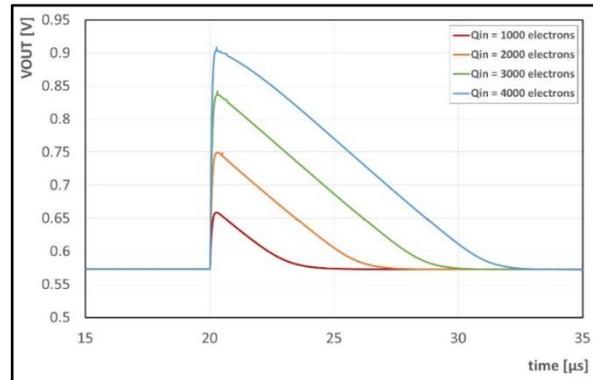
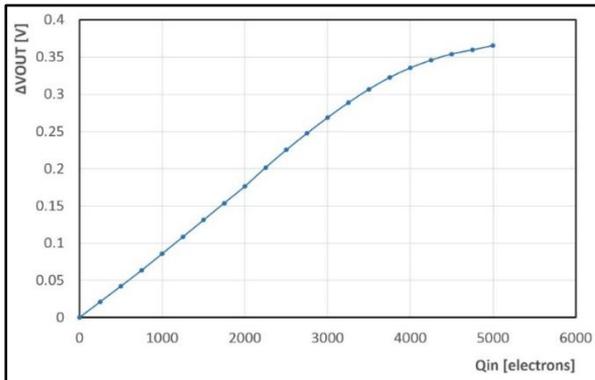
core amplifier („AMP”)

common bias circuit

one pixel



**Power consumption:** 1.4  $\mu$ W  
**Gain (cl):** 90  $\mu$ V/e<sup>-</sup>  
**Gain (ol):** 70.4 dB (3300)  
**Peaking time:** 150 ns (at 2 ke<sup>-</sup>)

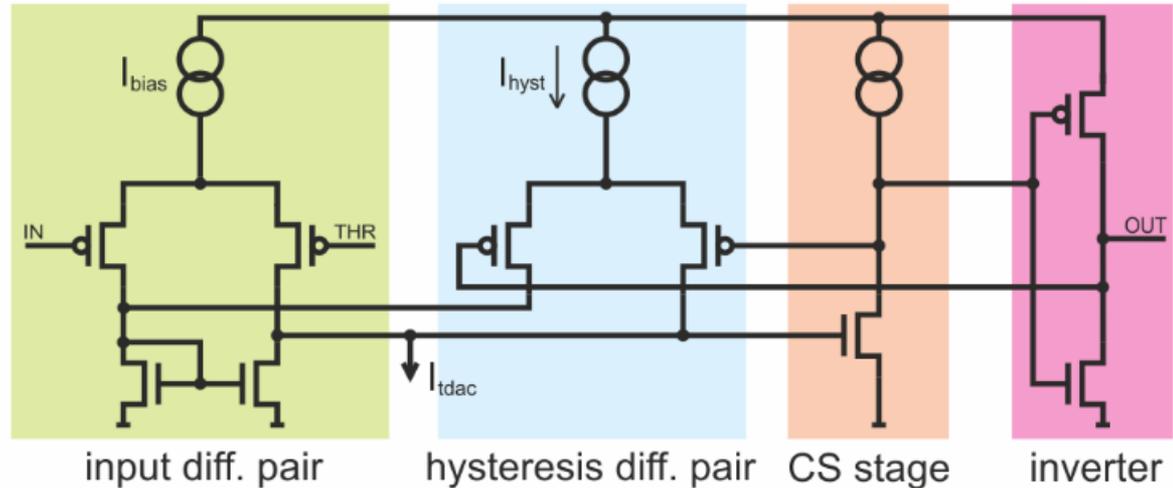


# Analog front-end – a closer look II.

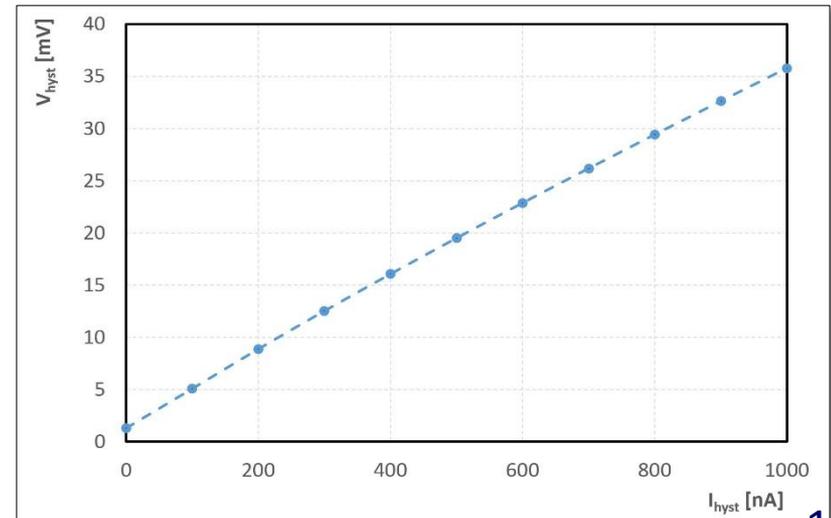
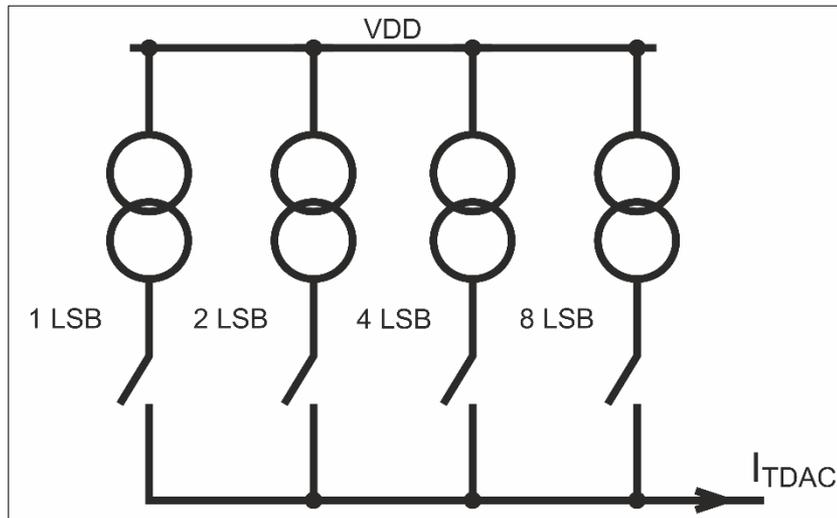
- Comparator with hysteresis and TDAC

- Parameters:

- power = 3.8  $\mu$ W
- offset:  $\mu = 3.1$  mV  
 $\sigma = 7.74$  mV
- hysteresis adjustable
- delay = 60 ns

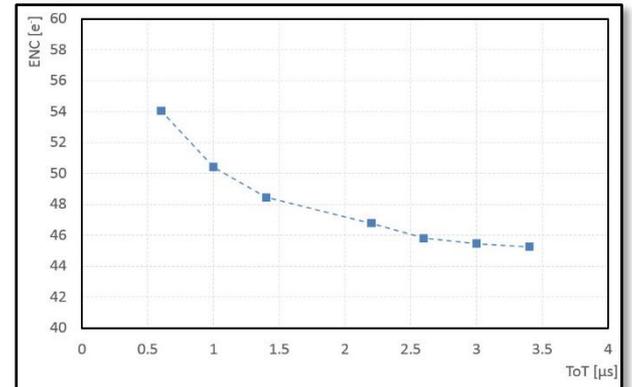
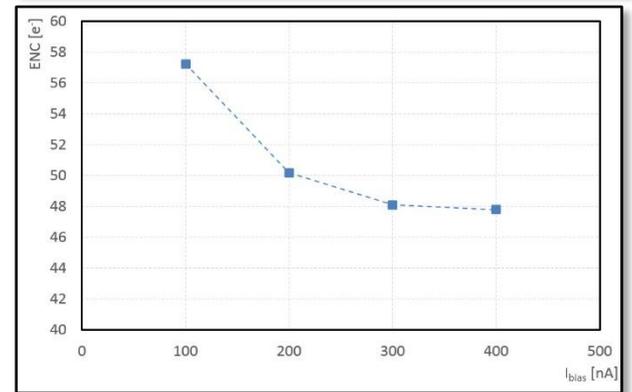
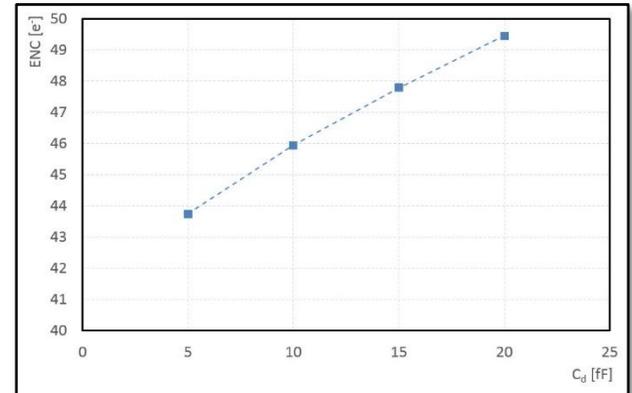
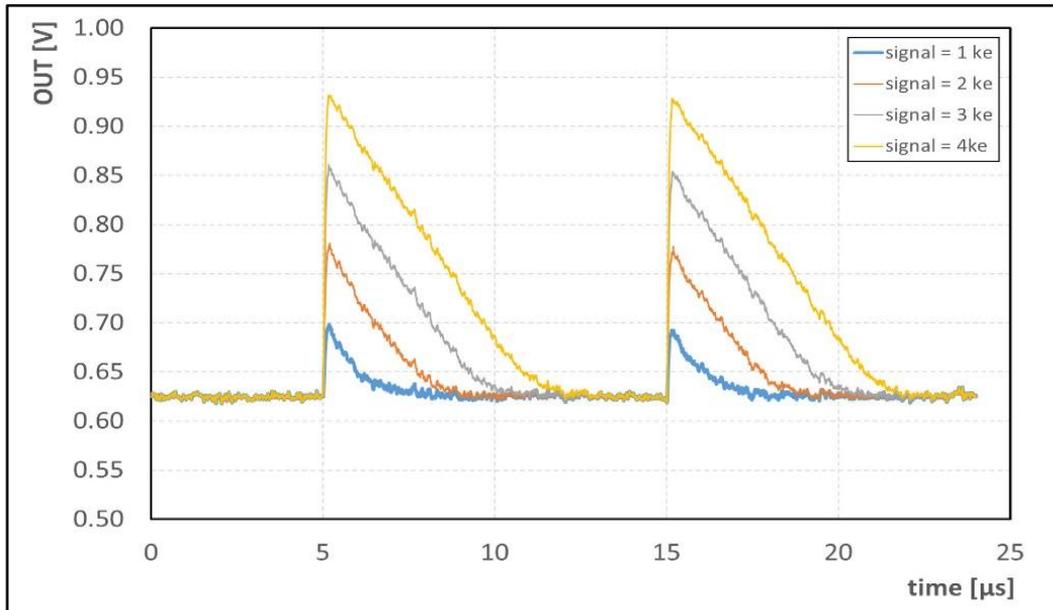


- Current steering TDAC



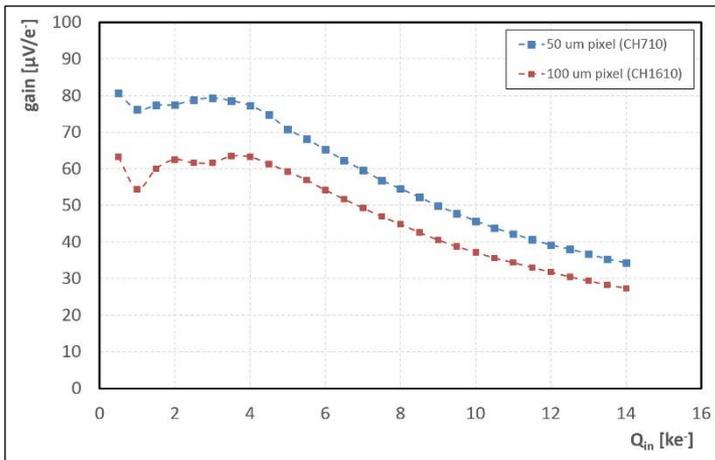
# Electronic noise simulation in time domain

- Electronic noise depends on many parameters
- Noise simulation in time domain as a function of:
  - sensor capacitance ( $C_d$ )
  - bias current of the CSA ( $I_{bias}$ )
  - discharge rate of the CSA(ToT at threshold =  $500 e^-$ , signal  $1000 e^-$ )



# Electronic noise measurement

- ENC is always present:  $ENC \sim C_d \sim \text{pixel size}$
- Noise determination from analog output



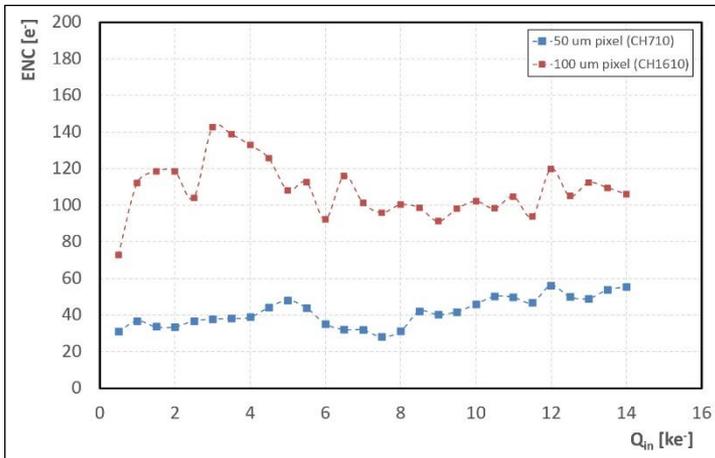
$$a_{CL} = \frac{1}{C_f} \cdot \frac{1}{\frac{1}{a_{OL}} \cdot \frac{C_d}{a_{OL} \cdot C_f}}$$

$a_{CL}$ .... closed loop gain

$a_{OL}$ .... open loop gain

$C_f$ .... feedback capacitance

$C_d$ .... sensor capacitance



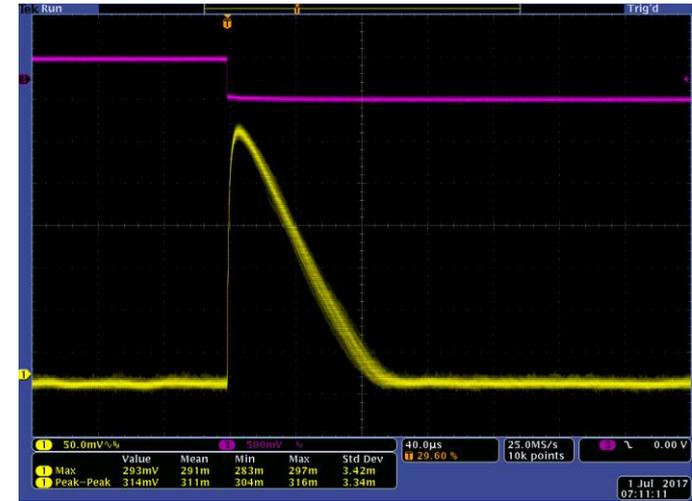
FD Hybrid pixel sensor:

$C_d \sim \text{pixel circumference}$

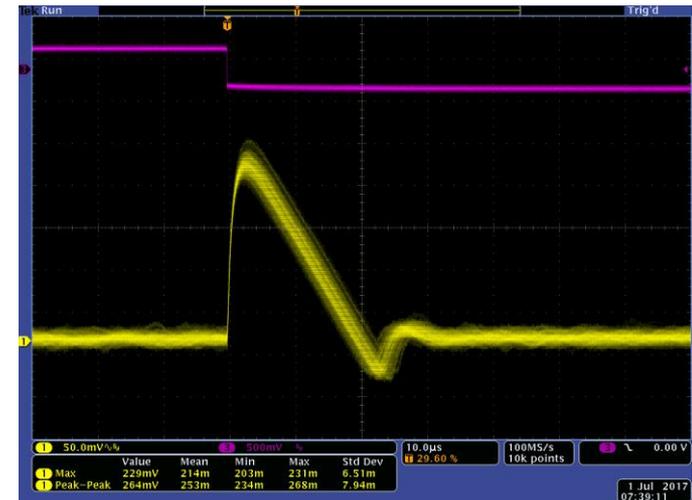
PD MAPS:

$C_d \sim \text{pixel area}$

## 4 $ke^-$ charge injection to 50 $\mu\text{m}$ pixel

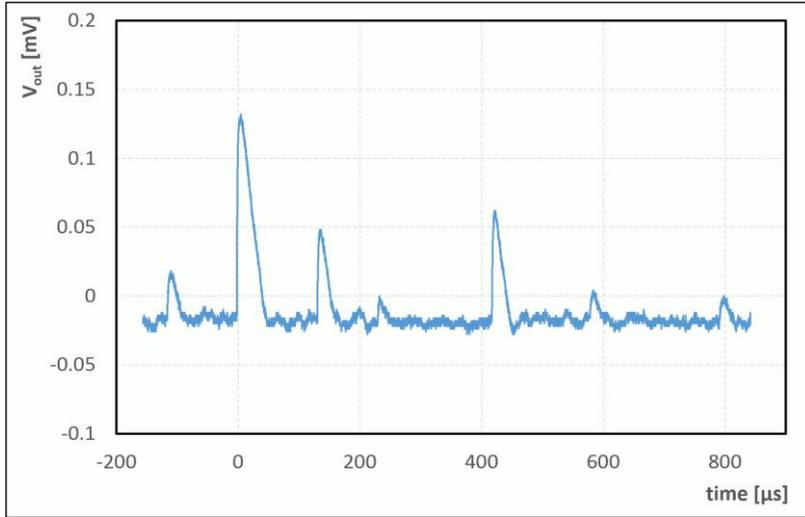


## 4 $ke^-$ charge injection to 100 $\mu\text{m}$ pixel

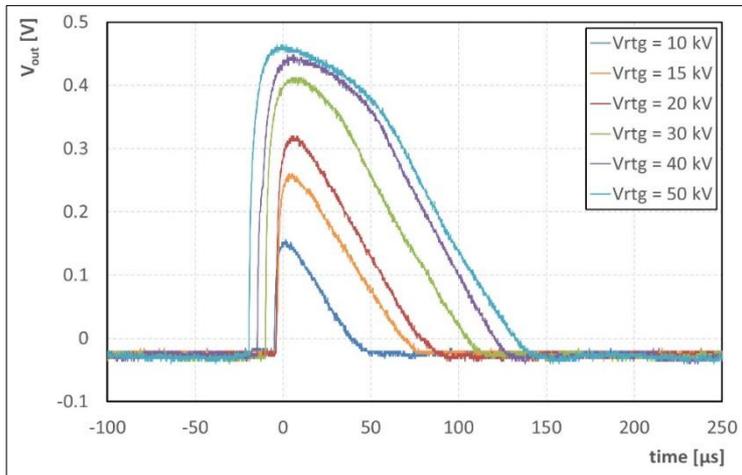


# First light to X-CHIP

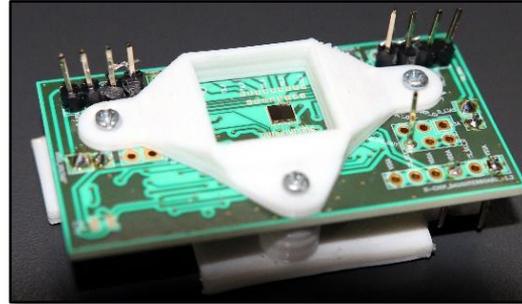
## Response to X-RAY radiation



## signal from “end-point” photons

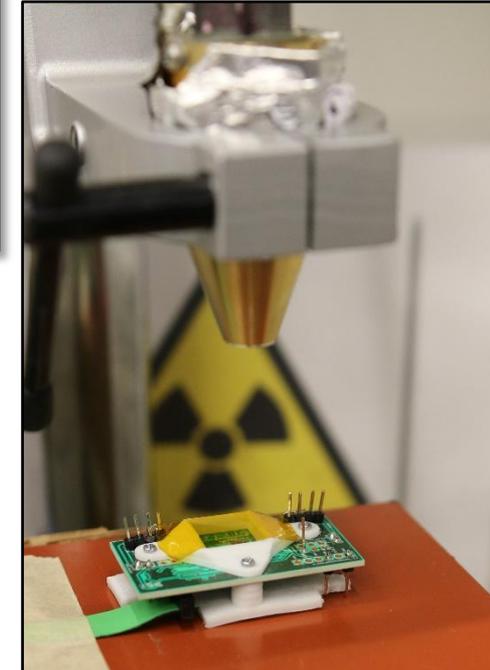


pcb with X-CHIP-02

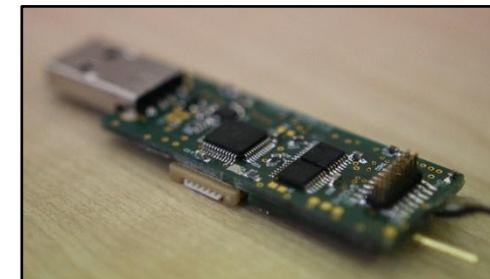
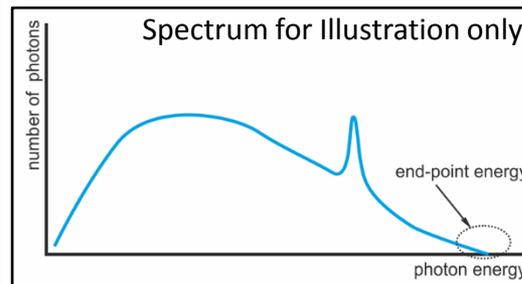


$V_{rtg}$ [kV]	$Q_{signal}$ [ke <sup>-</sup> ]	$\Delta V_{out}$ [mV]
10	2.74	179.5
15	4.11	283.1
20	5.48	318.8
25	6.75	398.2
30	8.22	438.4
35	9.59	462.9
40	10.96	458.2
45	12.33	475.8
50	13.70	490.9

X-RAY source 10-50 kV, max 200  $\mu$ A, Ag anode, Be window

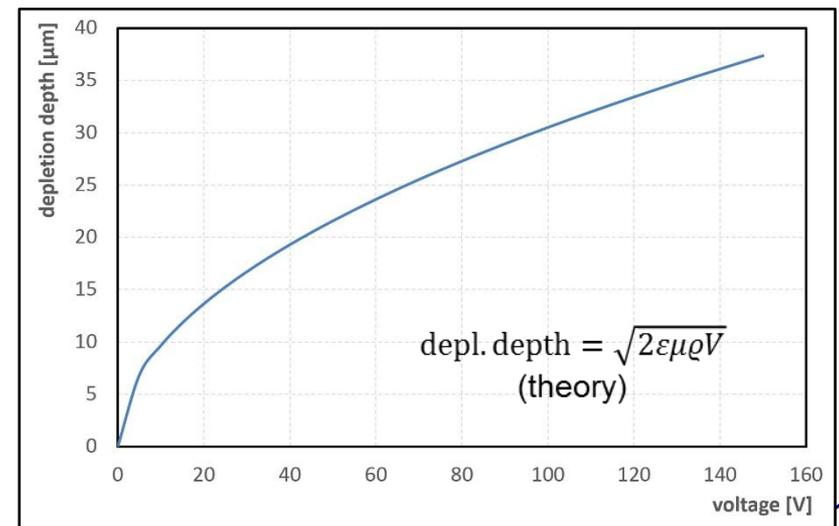
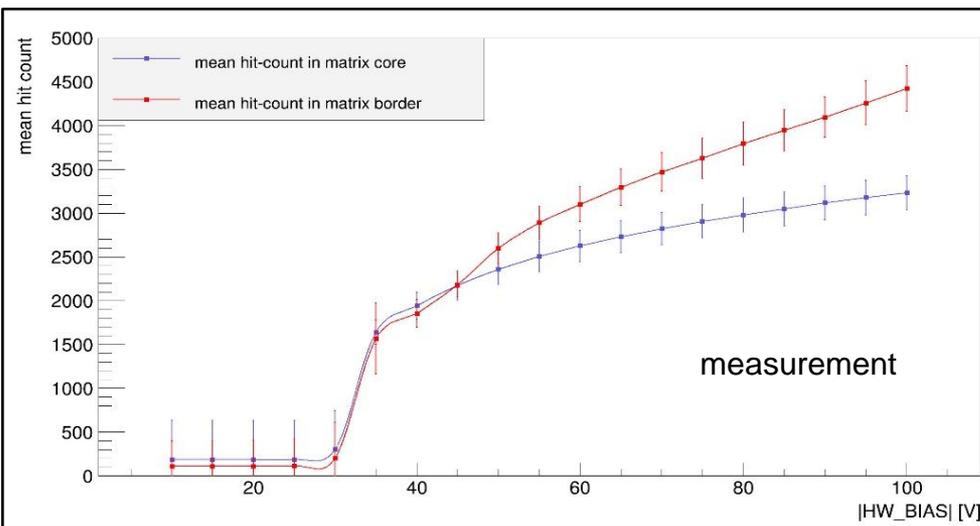
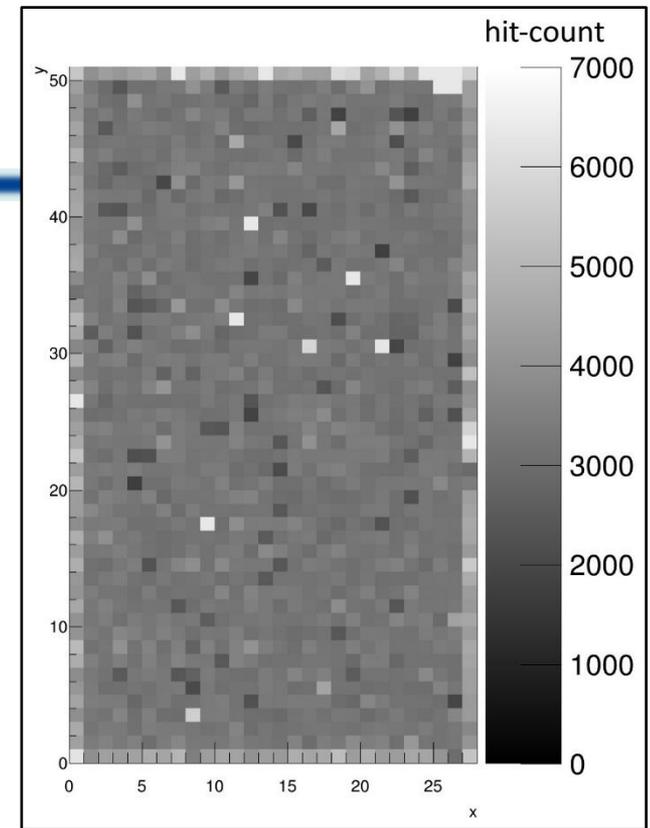
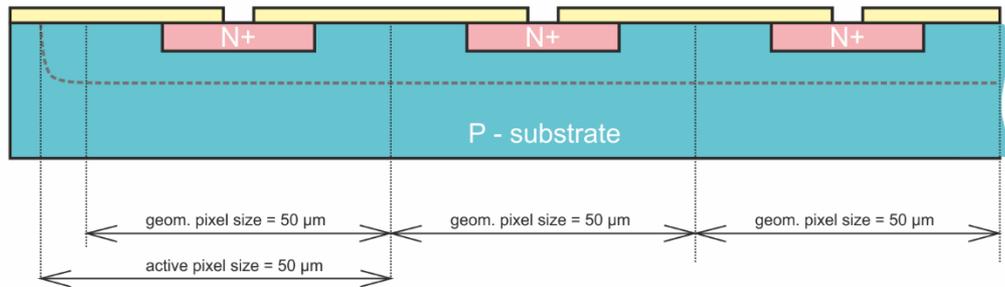


SURE – Simple USB Readout Equipment



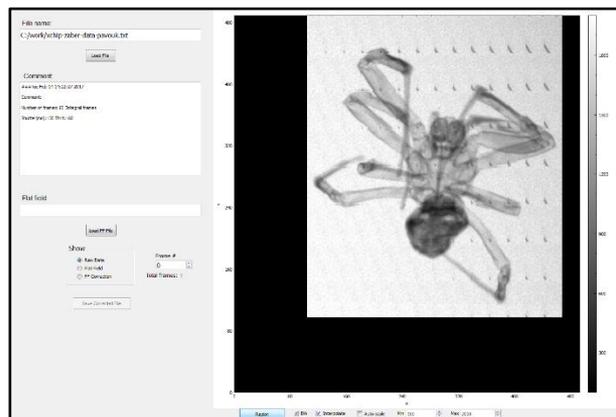
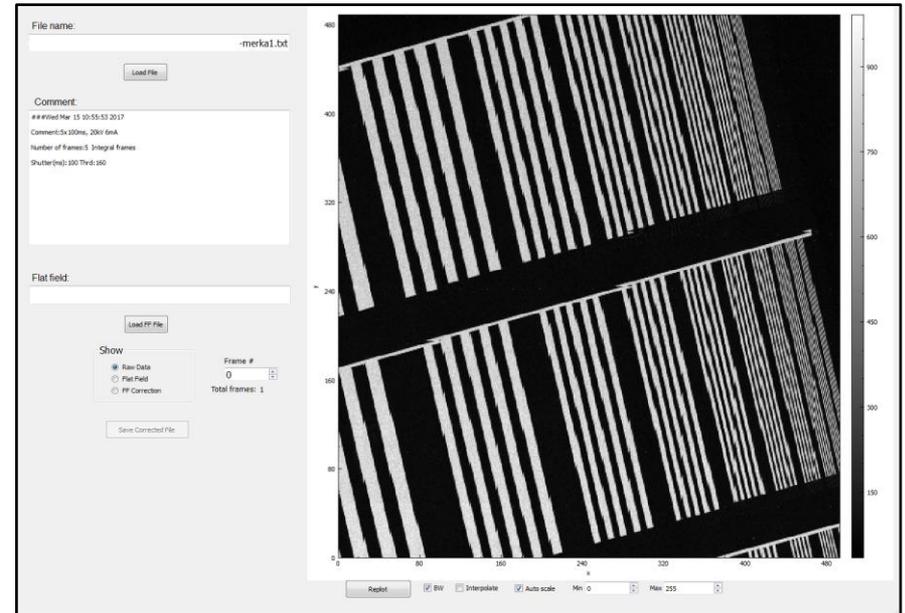
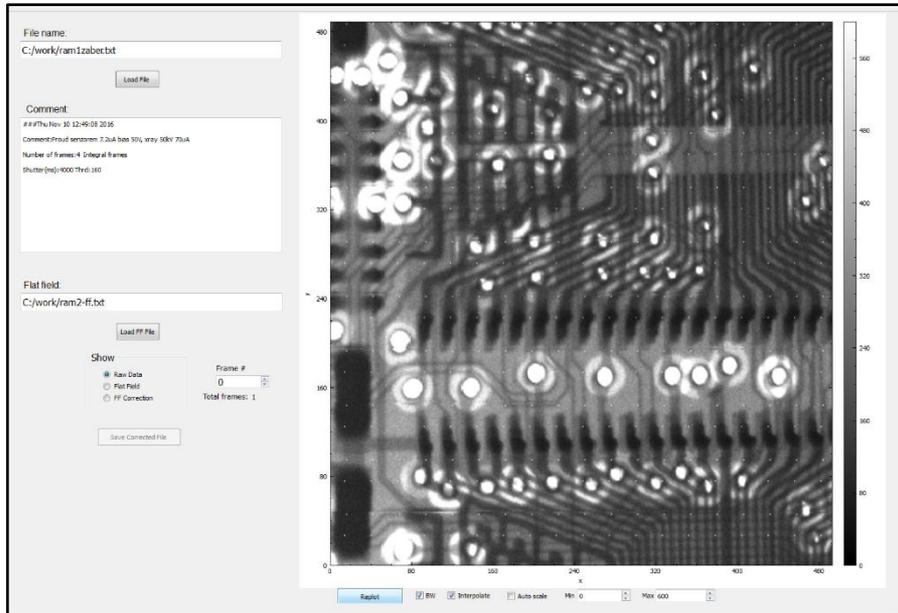
# Border effect

- Pixels along the edge give more hits compared to pixels inside the matrix
  - => border effect
  - => sign of large (possibly 100 %) fill factor



# First images

- X-CHIP mounted on moving table => area of about  $2 \times 2 \text{ cm}^2$  can be scanned



- Small chip area overcame by moving table
- Small dynamic range overcame by integration of several frames

This chip is already applicable for basic radiation imaging tasks

# Future development

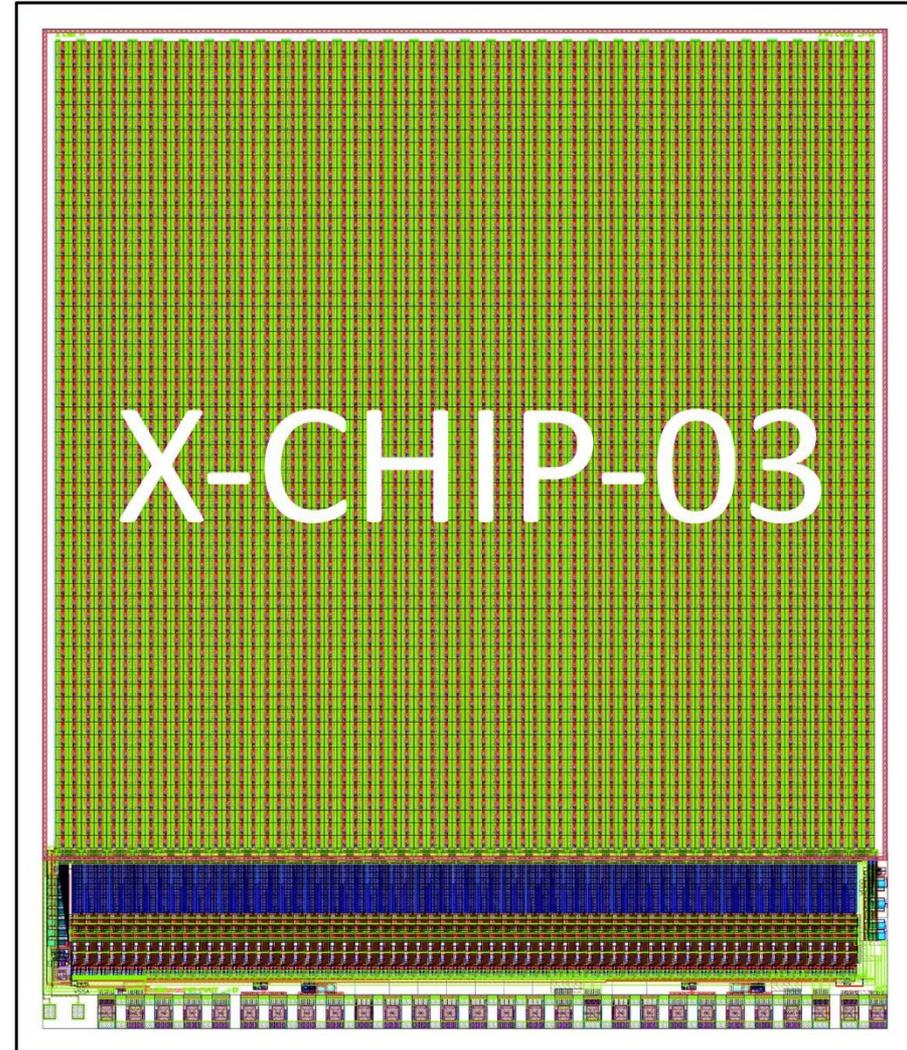
## ■ Limitations of X-CHIP-02:

- slow read-out (2 FPS)
- small dynamic range (8-bits)
- hit counting only

## ■ New version → X-CHIP-03:

- pixel matrix  $64 \times 64$  pixels ( $3.84 \times 3.84 \text{ mm}^2$ )
- fast read-out ( $\approx 400$  FPS)
- large dynamic range (16-bits)
- hit counting mode
- ADC mode
- complexity 3.6 mil. transistors

**Design submitted in May 2017**



# Acknowledgement

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- **Plenty of work done in short time**

- chip design
- PCB design
- USB read-out SURE
- SURE firmware
- control software
- .
- .
- .

- **I would like to thank to my colleagues for help to work on this project**

**This project has been supported Technology Agency of the Czech Republic under project number: TE01020069**

A scanning electron micrograph (SEM) of a microchip. The image shows a regular grid of small, circular pads. Larger, square-shaped structures are arranged in a grid pattern, each with a central square pad. The background is a light purple color, and the pads are a darker purple. The overall structure is highly regular and repetitive.

**Thank you for your attention**

50  $\mu\text{m}$